



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re application of

: **Confirmation No. 2779**

Hiromi OGASAWARA et al.

: Docket No. 2003\_0912A

Serial No. 10/616,996

: Group Art Unit 2813

Filed July 11, 2003

: Examiner Jennifer M. Dolan

METHOD OF MANUFACTURING A  
SEMICONDUCTOR ELEMENT

**Mail Stop: Amendment**

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of  
August 11, 2004.

The fee of \$1,020.00 is

(X) submitted herewith.

() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is  
enclosed.

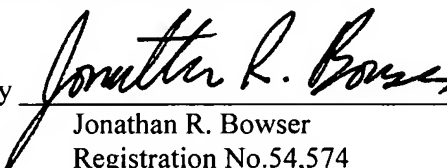
() Small entity status of this application is established by a Small Entity Status Assertion  
which

() is enclosed.

() has been previously submitted.

Respectfully submitted,

Hiromi OGASAWARA et al.

By 

Jonathan R. Bowser  
Registration No. 54,574  
Attorney for Applicants

02/14/2005 SZEWDIE1 00000080 10616996

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1020.00 DP

JRB/ck

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February 11, 2005